

OFFICIAL

AMENDMENT

Kindly amend the application as follows :

RECEIVED  
CENTRAL FAX CENTER

NOV 17 2003

In the claims

Claims showing the amendments made. Clean copy attached

1. (cancelled)
2. (cancelled)
3. (cancelled)
4. (cancelled)
5. (cancelled)
6. (cancelled)
7. (cancelled)
8. (cancelled)
9. (cancelled)
10. (cancelled)
11. (cancelled)
12. (cancelled)
13. (cancelled)
14. (currently amended) An ion source including a cathode, an anode, an ionisation region between said cathode and said anode, means for introducing an ionisable gas into said ionisation region, means for creating a potential difference between said cathode and said anode to produce a flow of electrons from said cathode toward said anode, said electron flow passing substantially through said ionisation region and causing ionisation of said gas, and means acting to expel ions created in said ionisation region from said ion source, wherein said anode has at least one surface exposed to said ionisation region, at least a portion of said at least one exposed surface comprising a layer of Titanium Nitride~~being of an electrically conductive non-oxidising material.~~

15. (cancelled)

16. (currently amended) An ion source according to claim 14 wherein said anode is annular and includes an inner surface sloping outwards in the direction of said cathode, said inner surface being exposed to said ionisation region and at least a portion of said inner surface comprising a layer of Titanium Nitride~~being of electrically conductive non-oxidising material.~~

17. (currently amended) An ion source according to claim 16 wherein substantially the entire inner surface of said anode is comprised of a layer of Titanium Nitride~~an electrically conductive non-oxidising material.~~

18. (currently amended) An ion source according to claim 16 wherein said gas introducing means includes an outlet member disposed substantially at the centre of said anode, said outlet member having a surface comprising a layer of Titanium Nitride~~of electrically conductive non-oxidising material.~~

**Claims (clean copy)**

1. (cancelled)
2. (cancelled)
3. (cancelled)
4. (cancelled)
5. (cancelled)
6. (cancelled)
7. (cancelled)
8. (cancelled)
9. (cancelled)
10. (cancelled)
11. (cancelled)
12. (cancelled)
13. (cancelled)
14. (currently amended) An ion source including a cathode, an anode, an ionisation region between said cathode and said anode, means for introducing an ionisable gas into said ionisation region, means for creating a potential difference between said cathode and said anode to produce a flow of electrons from said cathode toward said anode, said electron flow passing substantially through said ionisation region and causing ionisation of said gas, and means acting to expel ions created in said ionisation region from said ion source, wherein said anode has at least one surface exposed to said ionisation region, at least a portion of said at least one exposed surface comprising a layer of Titanium Nitride.
15. (cancelled)
16. (currently amended) An ion source according to claim 14 wherein said anode is annular and includes an inner surface sloping outwards in the direction of said cathode, said inner surface being exposed to said ionisation region and at least a portion of said inner surface comprising a layer of Titanium Nitride.

17. (currently amended) An ion source according to claim 16 wherein substantially the entire inner surface of said anode is comprised of a layer of Titanium Nitride.
18. (currently amended) An ion source according to claim 16 wherein said gas introducing means includes an outlet member disposed substantially at the centre of said anode, said outlet member having a surface comprising a layer of Titanium Nitride.